

ABSTRACT

METHOD FOR FABRICATION OF A MONOCRYSTALLINE PIEZOELECTRIC
LAYER AND MICROELECTRONIC, PHOTONIC OR OPTICAL DEVICE COMPRISING
SUCH A LAYER

The invention relates to a method of fabricating a layer (10) of a monocrystalline piezoelectric layer, characterised in that it comprises:

- the supply of a donor substrate (100) of said piezoelectric material,
- the supply of a receiving substrate (110),
- the transfer of a layer called a "germ layer" (102) from said donor substrate (100) onto the receiving substrate (110),
- implementation of an epitaxy of the piezoelectric material on the germ layer (102) until the required thickness for the monocrystalline piezoelectric layer (10) is obtained.

Figure 3E